

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	) Confirmation No.: 2015
Koichiro TANAKA et al.	) Examiner: Abdulfattah Mustapha
Serial No. 10/582,614	) Group Art Unit: 2812
Filed: June 12, 2006	)
For: LASER IRRADIATION METHOD,	)
LASER IRRADIATION APPARATUS,	)
AND METHOD FOR	)
MANUFACTURING	)
SEMICONDUCTOR DEVICE	)

**AMENDMENT**

Honorable Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated April 15, 2009, please consider the following amendments and remarks in connection with the above-identified application.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 6 of this paper.